006301 USA/Consilium/Consilium/DK Docket No.:

PATENT/OFFICIAI

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Badri N. KRISHNAMURTHY et al.

Serial No. 09/928,474

Group Art Unit: 2812

Filed: August 14, 2001

Examiner: Andre' C. Stevenson

For:

EXPERIMENT MANAGEMENT SYSTEM, METHOD AND MEDIUM

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such document.

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Serial No. 09/928,474

Please charge the fee of \$180.00 under 37 CFR 1.17(p) to Deposit Account No. 08-0219. The Commissioner is hereby authorized to charge any additional fees that may be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

HALE AND DORR LLP

Scott M. Alter

Registration No. 32,879

Reston Town Center 11951 Freedom Drive Reston, VA 20190

TEL (703) 654-7021 SMA/mgm

FAX (703) 654-7100

Date: 10/9/03

SHEET 1 OF 1 SERIAL NO. ATTY. DOCKET NO. 09/928,474 006301 INFORMATION DISCLOSURE USA/Consilium/Consilium/ CITATION IN AN DK APPLICATION (PTO-1449) APPLICANT Badri N. KRISHNAMURTHY et al. FILING DATE GROUP 2812 August 14, 2001 **U.S. PATENT DOCUMENTS EXAMINER'S** FILING DATE CLASS **SUBCLASS** INITIALS PATENT NO. DATE NAME 5,901,313 05/04/99 Wolf et al. 09/02/97 6,002,989 12/14/99 Shiba et al. 04/01/97 6,094,688 07/25/00 Mellen-Garnett et al. 03/12/98 6,340,602 01/22/02 Johnson et al. 02/12/01 02/05/02 05/15/00 6,345,288 Reed et al. 6,368,879 04/09/02 **Toprac** 09/22/99 US-2002/0107604 08/08/02 Riley et al. 12/06/00 10/22/02 01/04/00 6,470,230 Toprac et al. 03/19/01 Conchieri et al. 6,482,660 11/19/02 01/19/00 6,567,717 05/20/03 Krivokapic et al. **FOREIGN PATENT DOCUMENTS EXAMINER'S** Translation **SUBCLASS** COUNTRY **CLASS** INITIALS PATENT NO. DATE No WO 99/59200 🗸 11/18/99 WIPO X WO 01/52319 🗸 07/19/01 WIPO X

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

Williams, Randy, Dadi Gudmundsson, Kevin Monahan, Raman Nurani, Meryl Stoller and J. George Shanthikumar. October 1999. "Optimized Sample Planning for Wafer Defect Inspection," Semiconductor Manufacturing Conference Proceedings, 1999 IEEE International Symposium on Santa Clara, CA. Piscataway, NJ. pp. 43 - 46. 23 July 2003. Invitation to Pay Additional Fees and Communication Relating to the Results of the Partial

International Search for PCT/US02/19116.

01 August 2003. Written Opinion for PCT/US01/27406.

20 August 2003. Written Opinion for PCT/US01/22833.

EXAMINER DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.